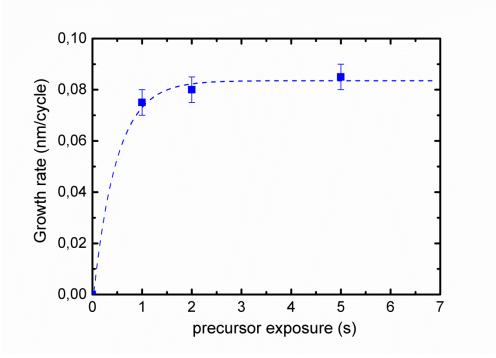
Supporting Information

Boron Nitride as a novel support for highly stable Palladium nanocatalysts by Atomic Layer <u>Deposition</u>

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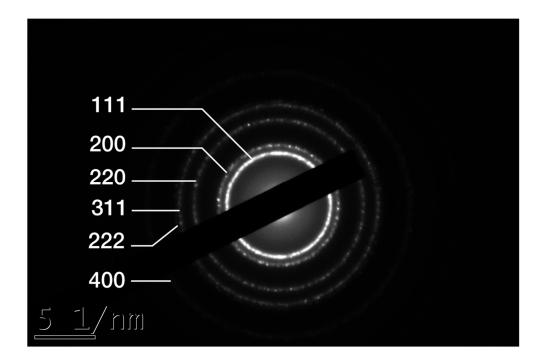
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<u>Figure S1</u>: Saturation curve of the BN film growth as a function of the BBr₃ exposure time, depicting the saturated growth of the film.

<u>Table S1</u>: Properties of BN films prepared by ALD using BBr₃ as precursor and NH₃ as coreactant at 750°C. The substrates were Si(100) wafers and the substrate temperature was 750°C. In situ spectroscopic ellipsometry (SE), X-Ray reflectometry (XRR), atomic force microscopy (AFM), X-Ray photoelectron spectroscopy (XPS) measurements were used for the analysis. The films were 25 nm thick for all analysis.

Properties	Value	Analysis technique
Growth-per-cycle (Å/cycle)	0.8±0.1	SE
Mass density (g/cm ³)	2.2±0.3	XRR
RMS roughness (nm)	3.5±2	AFM
C content (at.%)	4±3	XPS
O content (at.%)	7±3	XPS



Crystal	Diameter of the diffraction rings (nm ⁻¹)	d (Å)	Crystal planes
Pd	8.46	2.36	111
	9.90	2.02	200
	13.93	1.44	220
	16.34	1.22	311
	17.21	1.16	222
	21.86	0.91	400

<u>Figure S2</u>: Selected area electron diffraction of a BN/Pd NPs sample prepared using 300 cycles of the Pd ALD process, corresponding to Figure 1c. The substrates used were Si_3N_4 TEM windows covered with 15 nm of BN. The table corresponds to the indexing of the diffraction rings.